

Form 1449 (Modified)				Atty Docket No. NOVLP050D1/NVLS- 000682D1	Application No.: NEW
Information Disclosure Statement By Applicant				Applicant: Hill et al.	10/803,234
(Use Several Sheets if Necessary)				Filing Date HEREWITH	Group UNASSIGNED

U.S. Patent and Published Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
W	A1	6,329,062	12/11/01	Gaynor			
	A2	6,268,276	7/31/01	Chan et al.			
	A3	6,177,329	1/23/01	Pang			
	A4	5,920,790	07/99	Wetzel et al.			
DL	A5	2003/0119307	06/03	Bekiaris et al.			

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
DL	B1	WO95/07543	03/16/95	WIPO			X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
DL	C1	R.D. Miller et al., "Phase-Separated Inorganic-Organic Hybrids for Microelectronic Applications," MRS Bulletin, October 1997, Pages 44-48
	C2	Jin et al., "Nanoporous Silica as an Ultralow-k Dielectric," MRS Bulletin, October 1997, Pages 39-42
	C3	Cleempur et al., "Dielectric Films With Low Dielectric Constants," Application Serial No.: 09/727,796, filed November 30, 2000,
	C4	Asoh et al., "Fabrication of Ideally Ordered Anodic Porous Alumina with 63 nm Hole Periodicity Using Sulfuric Acid," J. Vac. Sci. Technol. B 19(2), Mar/Apr 2001, Pages 569-572
	C5	Asoh et al., "Conditions for Fabrication of Ideally Ordered Anodic Porous Alumina Using Pretextured Al," Journal of the Electrochemica Society, 148 (4) B152-B156 (2001) Pages B152-B156
	C6	Holland et al., "Nonlithographic Technique for the Production of Large Area High Density Gridded Field Sources," J. Vac. Sci. Technol. B 17(2), Mar/Apr. 1999, Pages 580-582
DL	C7	Masuda et al. "Highly Ordered Nanochannel-Array Architecture in Anodic Alumina," App. Phys. Lett. 71(19), November 1997, Pages 2770-2772

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b1	C8	Clube et al., "White Paper from Holotronic Technologies SA; downloaded from www.hdotronic.com/whitepaper/fine-patt.pdf on March 12, 2002
1	C9	Meli et al., "Self-Assembled Masks for the Transfer of Nanometer-Scale Patterns into Surfaces: Characterization by AFM and LFM", Nano Letters, Vol. 2, No. 2, 2002, 131-135
b1	C10	"Shipley Claims Porous Low K Dielectric Breakthrough," Press Release March 17, 2003.
Examiner		Date Considered 7/7/05

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.